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Fully Automated High Temperature WLR Test Solutions with an Integrated Probe Card Changer

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Community of On-Wafer Test & Reliability Experts

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- 1. Advanced Semiconductor Test: Short Introduction
- 2. Wafer Prober Automation: Product Overview
- 3. Wafer Prober Integration of automated probe card exchanger: Indexer[™] from Celadon Systems
- 4. Indexer[™]from Dalton





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MPI's Advanced Semiconductor Test Division

At the glance:

- Started in 2013...from "zero" and developed: >40x different types of base probe stations >50x patents and patent pending's (incl. on manual stations) >150x different RF probes (up to 220 GHz) & >20x cal. substrates 2x SENTIO[®] & QAlibria[®] software solutions
- Addressing various engineering and niche production (PIC, RF, HP) markets
- Market leader in certain regions (EMEA, China) and market segments (e.g. RF & mmW, Load pull, 1/f...)



MPI AST Main Markets and Applications













AST Product Overview

1. Advanced Wafer Probe System

2. RF Probes & Accessories



3. Prober & Calibration Software



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MPI Engineering Probe Systems

Offers 20 Different Manual Probe Stations







MPI Engineering Probe Systems (cont.)

Offers 21 Different Automated Probe Stations





8x Models in 24/7 Production

CEL^DO[™] TITAN[™] RF Probes Technology Overview



Wide Range of RF Probes





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26-220 GHz

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MPI TS3XXX Series: The Most Versatile Portfolio

Base Systems Main Features	TS3000	TS3000-IFE	TS3000-SE / TS3000-HP	TS3500	TS3500-IFE	TS3500-SE* / TS3500-НР	
XY-Stage (HR-Option*)	310 x 320 mm			305 x 520 mm			
Thermal Range	20300°C	-60300°C		20300°C	-60300°C		
Chamber	No	IceFreeEnvironment™	ShielDEnvironment™	No	IceFreeEnvironment™	ShielDEnvironment™	
PTPA	Νο			Option			
WaferWallet [®] Family	Νο			Option			



- MPI TS3000-SE MPI TS3000-IFE MPI TS3000
- Unsurpassed upgrade path in the field
- Various configurations for various budgets and various applications

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WaferWallet[®] Family









For Device Modeling & WLR Labs

Designed with five individual trays for manual, ergonomic loading of **150, 200, or 300 mm** "modeling" wafers

No cassette handling, flexible set-ups, cost-effective automation



(RF, Celadon)

- Hot- or cold wafer swapping (soaking time) Pre-aligner, Wafer-ID reader optional

WaferWallet[®] - The Ultimate Automation for the Lab

- •Automated tests at multiple temperatures









- Designed for direct test head docking \rightarrow targeting 25um pitch probing
- **OHT** option



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MPI WaferWallet[®] Family with Celadon's Indexer[™]

■Celadon Indexer[™] → Automated Probe Card Changer Combining Multiple Wafers with Multiple Probe Cards (VC20s) •Fully Automatically (remotely accessible over SENTIO[®]) → Unsurpassed Automation and Flexibility





 \checkmark





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SENTIO[®] Test Executive Assist Manager

GUI and remote interface to configure test automation including:

- Wafers (systems with loader)
- Alignment options (PTPA)
- Temperatures
- Soak times

■VC20 Probe cards (Indexer[™])







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Use Case of Test Executive Assist Manager

- For systems with MHUs: WaferWallet[®] Family
- Simplify test executive development
 - Fewer remote commands required
 - Implement automation procedures to SENTIO[®]
- Simplify management of complex test setups
 - Define wafer selection
 - Define probe cards for different wafers/"off-line" measurements
 - Define test setups
 - Memorize wafer selection & test setup on the prober
 - Managing the soak time at different test temperatures





Phase I - Virtual Wafer Carriers

- Virtual carrier is like lot in production environments
- Physical location of wafers becomes flexible



- Each virtual wafer carrier has the potential to contain: One to 5 or to 25 wafers
- Enables convenient integration into test executive software for production environments









SENTIO[®] Test Executive Assist Manager Roadmap

Support multi-wafer processing \checkmark GUI implementation Remote interface

Github available for free

Phase II:

- Automated alignments
- Probe cards automation (Indexer[™])
- Temperature automation





Celadon Indexer Purpose and Valuation Dalton Roehl

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CELADON The Celadon Indexer

The Indexer is an Automatic Probe Card Changer that increases throughput of Devices by lowering operator interaction time.

- Holds up to 5x Celadon VC20E Probe Cores
- -65 to 200C Operational Temperature
- Easily Replaceable and Swappable VC20E Probe Cores
- Touchless Inductance Sensors for measuring active position
- Highly customizable for specific test equipment and requirements
- Remote control through TCP-IP commands
- Interlock for Safe Testing



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Indexer – Lifetime Validation

The Celadon Indexer was validated for lifetime cycle count on an MPI TS3500 at Room **Temperature and 200C.**

- At Room Temperature, the system achieved 100,000 cycles over constant use for 22 days with 0 failures detected.
- At 200C, the system achieved 40,000 cycles over constant use for 5 days with 0 failures detected.



Current Cycle count Results on the Lifetime Test							
	Pass "Initial"	Fail "Initial"	Pass "Index"	Fail "Index"	Pass "Final"	Fail "Final"	
Room Temp	106,400	0	İ 06,400	0	106,400	0	
200C	41,700	0	41,700	0	41,700	0	

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Indexer – Electrical Validation

The electrical performance of the Celadon Indexer was compared to the standard Celadon 45E.

- Signal to Signal Leakage of <**5fA/V** at 10s and 25C
- Signal to Guard Isolation of >**1TΩ** at 5s, 100V and 25C







EELADO Indexer – Electrical Validation



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El	Electrical Performance						
Time	Leakage	Isolation					
[s]	[fA/V]	$[T\Omega]$					
	Indexer IDX5I						
1	7.63	3.22					
3	4.25	5.95					
5	3.89	8.20					
7	3.69						
10	3.62						
	45E PCI						
1	6.93	3.79					
3	4.23	6.16					
5	3.88	10.03					
7	3.74						
10	3.67						

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Indexer – Thermal Drift Validation

The Celadon Indexer Thermal Drift Performance

- System heated to 200C until stable
- Chuck moved to off-axis camera (North) for 2min cooling effect
- Move chuck back and measure X/Y/Z shift due to shrink

Based on the position of the wafer, the maximum Z shrink was about 61um with an unmeasurable X/Y shift.



Figure: Measured Z-shrink of the probe tips. (Left) Expectation of Z expansion on a wafer (Right) © 2025 Celadon Systems, Inc.



Figure: X/Y shift of scrubs after the cooling 2min period



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For Your Attention

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Sophisticated piezo MEMS wafer-level testing technologies that meet the semiconductor industry's demanding requirements

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ADVANCED CUSTOMIZED CHARACTERIZATION TECHNOLOGIES





- Introduction
- Groundbreaking wafer-level reliability solution
- Displacement measurements on piezoelectric materials
- Memory Testing solutions
- Summary



Introduction

- aixACCT systems GmbH, founded in 1999 in Aachen, Germany from aix la chapelle ("city with a chapel", French for Aachen)
 ACCT Advanced Customized Characterization Technologies
- Over 40 employees serving over 500 worldwide customers with more than 2600 units sold

http://www.aixacct.com

Piezoelectric Pyroelectric Ferroelectric Multiferroics Resistive Thermoelectrics

Thin films MEMS Bulk materials Multilayer Single crystals Polymers

Academia National Labs R&D Centers Industry



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Wafer-level Durability Analyzer measurement system aixWDA

Key Specs

- Temperature ranges: from -60C to 350C
- Sample dimensions: full wafer, up to 200mm
- Parallel measurements up to 64 channels using specialized probe card
- Heating rate > 8K/min over the full temperature range
- <u>maintaining constant contact over temperature</u>
- Automatic wafer loader available for fast turnaround





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aixWDA measurement system

aixACCT measurement system controls the overall function

aixACCT is responsible for overall functionality and performance

aixACCT has selected strong cooperation partners for successful project result: MPI, Celadon



MPI TS2000IFE Prober and Loader including ERS temperature chuck (-60C to 350C, constant ramp function) with integration support by ATV

Celadon high temperature Probecard with TDS

Dedicated parallel TSDC and Q-DLTS test electronics Full Automation

Thermal drift compensation

Overtravel protection

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Automation Assistant control software





- New MPI/ERS Thermochuck with extended temperature range -60...350°C with fast ramp function
- >8K/min heating
- >5K/min cooling



Minimized XY chuck drift verified by
 MPI

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The relative offsets between the glass and the chuck from -50°C to 350°C (center)

Glass and Chuck



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New Celadon Probecard TDS



Integrated into Celadon T300 probecard





• Pre-Experiments carried out by ATV



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- Celadon T90 test probecard
- Heating chuck to 300C
- Contact maintained manually (stepwise) and drift of more than 400um to be compensated



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- Joined into fully automated control solution by aixACCT
 - in-situ z-drift compensation
 - fully automated overtravel detection and failure handling avoids damage
 - measurements across entire wafer from -60C to 350C possible with highly stable electrical contact for continuous measurements at 8K/min without recontacting







- Application in Piezo for a world leading MEMS foundry
 - TSDC = Thermally Stimulated Depolarization Current

<u>Call it:</u> Time Saving Defect Characterization ?

Why? Let me explain in a minute!



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- Material defects, such as oxygen vacancies in PZT (PbZrTiO₃), lead to unreliable device performance
- Usually: HALT (highly accelerated lifetime testing) for 1000hrs is carried out under harsh conditions to predict lifetime
- TSDC obtains information about vacancies or other defects
 - <u>Peaks</u> in the current response correlate to vacancies



Lifetime prediction possible without time consuming HALT



CDP , Center of Dielectrics and Piezoelectrics at Pennstate university https://cdp.ncsu.edu/



Q-DLTS (charge based Deep Level Transient Spectroscopy)

Q-DLTS measures the transient current decrease at a range of temperatures after an electrical voltage pulse was applied to the sample.



- DLTS signal characteristic for material defects in thin film
 - Temperature stepping required for peak resolution
 - High test speed by temperature stepping without recontacting



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- Electrical contact during thermal ramp enables outstanding possibilities in terms of device and material characterization
 - High throughput measurements possible
 - No need of separating probe card and wafer
 - No need of realignment process

Gamechanger: Testing time reduced from weeks to hours





Displacement measurements



• Double-Beam Laser Interferometer (DBLI)



- determine d33 (displacement) with laser on wafer-level
- Laser beam guided onto backside and sample using the same beam path
- Influence of substrate bending can be eliminated and only piezo response of the sample is measured



Displacement measurements

- Outstanding precision
- **Gold Standard** for piezoelectric film characterization
- Piezoelectric coefficient d₃₃
 obtained for x-cut quartz
 - Well known d₃₃=2.3pm/V
- Linear response for different excitation voltages obtained by DBLI
 - Achieves **200fm** resolution
 - No readjustment of optics required







Memory Testing solutions

- Resistive Memory Testing
 - 64 Output Channels, 32 Input Channels
 - Individually addressable & individual waveform each channel
 - Characterizes resistive switching in 16x16 matrix
 - Import demand: Ultra-fast current compliance to avoid device failure
 - Programable current limit with response down to 5ns and minimal overshoot

aixACCT measurement equipment controls the overall function of the system





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- New Test System for high throughput lifetime testing was developed
 - We thank MPI, ATV, and Celadon for their cooperation in realizing this first-of-its-kind aixWDA system!
 - Wafer-level TSDC and Q-DLTS in one system
 - Measurement of electrical current in parallel on wafer-level under thermal ramp in contact!
- Standardized Piezo testing
- Emerging technologies testing
- aixACCT is complete solution provider







An integrated system to Enable Highly Stable Full Wafer Reliability Testing of MicroLEDS

Ian Cheng AutomatisierungsTechnik Voigt GmbH

WE MEASURE WITH PLEASURE

ATV Introduction

- June 2000 founded in Germany
- 2009 Keithley distribution partner
- 2014 MPI & Celadon distribution partner for on-wafer test



- 2022 building extension with demo & training center
- 30 employees, software experts, hardware, application & service engineers





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ATV System

ATV fill in where the su

- Software / Hardware engi
- **Measurement Instrument**
- **Prober systems / Probe ca** •
- Service team



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•MEMS

Community of

Reliability

Experts

On-Wafer Test &

WLR MicroLED Challenges





Time-intensive

- Time intensive full wafer measurement to 3 days
- Ultra-stable optical and electrical measurement

Test equipment challenges

- Parallel high current, continuous measurement setup
- Precise contact over full wafer

Complex data processing

- Massive optical and electrical data collection
- Difficult failure mode analysis

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Case Study







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T300 ButtonTile™



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Case Study







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ATV, MPI, Celadon











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About ATV integrations...







Thank you! Questions?









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